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## **Theoretical study of a self-sustained CMOS-integrated nano-oscillator**

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### **1 Introduction**

Over the last ten years, the progress of Nanoelectromechanical systems (NEMS) fabrication has opened new possibilities for the use of NEMS as high-performance, low-cost, compact sensors [1]. In NEMS resonators-based sensors, the resonant frequency depends upon the physical parameter to be measured [2]. To track dynamically the time-varying resonant frequency of the NEMS, one approach consists in embedding the NEMS in a self-oscillating loop so that it oscillates at its resonant frequency. The resonator chosen in this study uses electrostatic actuation and capacitive detection. This has the advantage of having a relatively simple implementation and good transduction efficiency. Furthermore, this actuation/detection scheme makes possible the monolithical integration of the NEMS resonator with a dedicated CMOS circuit. Co-integrated sensors have higher signalto-noise ratios since parasitic capacitances are drastically reduced. Examples of cointegrated NEMS resonators are presented in [3-5].

The main contribution of this work is the design of a NEMS/CMOS oscillator (NEMS as resonant element, CMOS circuit as sustaining amplifier) with a very simple amplifying circuit based on a single active transistor. The design of the electronics and the oscillator steady-state response are theoretically studied. The micro/nanomechanical resonator is described in section 2, the oscillation conditions and the CMOS sustaining amplifier are respectively analyzed in sections 3 and 4. Finally, the steady-state regime of the oscillator is determined by using a describing function method in section 5.

## **2 Description of the mechanical resonator**

Figure 1 schemes the oscillator comprising a NEMS resonator and a CMOS circuit. The NEMS is a 3-port doubly-clamped beam resonator which converts the input voltage into a mechanical motion which is then detected and converted back into a voltage through a capacitive detection.  $F$  is the electrostatic force applied to the beam and y the resulting in-plane (transverse) motion of the beam. The purpose of the sustaining amplifier circuit is to amplify and to shift the phase of the NEMS output voltage so that oscillation builds up. The resonator has the following dimensions: 14.8 $\mu$ m long ( $\eta$ , 250 $\mu$ m wide (w) and 1 $\mu$ m thick (h). The expected quality factor (Q) of this device in vacuum is 1000. The resonating beam is polarized by a DC voltage  $(V_B)$ . The gap  $(q)$  between the beam and each of the detection and actuation

electrodes is 250nm. According to these dimensions, the resonance of the fundamental in-plane flexural mode is approximately  $f_0=10MHz$ .



Figure 1: Oscillator schematic

The following notations are used:  $V_N$  is the voltage at the input of the NEMS and  $V_N$  is the AC component of  $V_N$ .  $V_e$  is the voltage at the input of the electronic circuit and  $V_e$ is the AC component of  $V_e$ .  $V_{DC}=11.5$  V is the DC component of  $V_{B}-V_{N}$ .

Assuming  $v_N, v_e \ll v_{DC}$ , y $\ll g$  and the DC component of  $V_N$  and  $V_e$  are equal, the transduction behavior of the mechanical beam can be approximated to:

$$
m\ddot{y} + c\dot{y} + (k - k_e)y = -\frac{C_0 V_{DC}}{g} (v_e - v_N),
$$
\n(1)

where m is the effective mass, k and  $k_e$  are respectively the mechanical and electrostatic stiffness, c the dissipation coefficient ( $c = \sqrt{km}/Q$ ) and  $C_0 = \varepsilon_0 \ln l/g$ .

Assuming that the input of the electronic feedback circuit is mostly capacitive, the output voltage of the NEMS  $v_e$  can be calculated through (here  $y \ll q$ ): g y  $\mathcal{C}_{0}^{(n)}$  $v_e = -V_D C \eta_D \frac{C}{C}$  $e = -V_D c \eta_D \frac{c_0}{C_{in}} \frac{y}{g}$  where  $C_{in}$  is the total capacitance (mainly parasitic) at the NEMS

output (i.e. at the circuit input) and  $\eta_D \approx 0.52$  is a parameter depending on the mechanical mode excited. The transfer function of the NEMS  $(H_{NFMS})$  has the following expression:

$$
H_{nems} = \frac{v_e}{v_n} = \frac{(C_0 V_{DC} / g)^2 \eta_D}{(k - k_e)C_{in} + (C_0 V_{DC} / g)^2} \frac{1}{1 + jf/(Qf_0) - (f/f_0)^2}.
$$
 (2)

The NEMS behaves as a bandpass filter with a high quality factor. Therefore at the fundamental frequency, the gain is maximum and the phase delay between the input voltage and the NEMS output voltage is equal to -π/2. The NEMS gain and phase at the resonance frequency  $(f=f_0)$  are:

$$
|H_{nems}(j\omega_0)| = g_{nems} \approx 0.93 \text{ and } angle(H_{nems}(j\omega_0)) = \psi_{nems} = -\pi/2
$$
 (3)

In a properly designed system, the beam should oscillate at a frequency close to  $f_0$ . To determine with accuracy the oscillator behavior close to its working frequency, one can compute the Taylor expansion of  $H_{nems}$  when f is close to  $f_0$ . This yields:

$$
G_{nems} \approx -g_{nems} \left( 1 - 2Q^2 \frac{(f - f_0)^2}{f_0^2} \right), \ \psi_{nems} = -\pi/2 - 2Q \frac{f - f_0}{f_0}, \tag{4}
$$

where  $G_{nems}(f)$  and  $\Psi_{nems}(f)$  are the amplitude and phase responses of the NEMS. Equation (4) lead to:

$$
G_{nems} = g_{nems} \left[ 1 - \frac{(\pi / 2 + \psi_{nems})^2}{2} \right]
$$
 (5)

Note that, because of the large value of Q,  $\Psi_{nems}$  can be fairly different from -π/2 and f still very close to  $f_0$ .

We will now discuss the resulting implications on the design rules of the electronic circuit in order to build up the oscillations.

#### **3 Oscillation condition**

To determine the oscillation conditions of a closed-loop system, one must consider the open loop transfer function  $H_{OL}$  of the NEMS and its electronics.  $H_{OL}$  is the product of the transfer function of the NEMS and that of the sustaining electronic  $H<sub>elec</sub>$ . According to the Barkhausen criterion, oscillations start building up when

$$
\text{Re}(H_{\text{nems}} \times H_{elec}) > 1 \text{ and } \text{Im}(H_{\text{nems}} \times H_{elec}) = 0, \tag{6}
$$

and stabilize when: 
$$
H_{\text{nems}} \times H_{elec} = 1
$$
. (7)

The electronic feedback circuit must amplify and shift the phase of  $v<sub>e</sub>$  in order to satisfy the Barkausen criterion. From (2) and (3),  $H_{elec}$  must have a gain superior to  $1/\gamma_{\text{nems}}$  and a phase of  $\psi_{\text{elec}} = \pi/2$  to ensure oscillation at  $f_0$ . Once the oscillation builds up, its amplitude must be somehow controlled otherwise when the amplitude reaches the pull-in threshold, the beam can collapse by sticking. One possible approach consists in dynamically adapting the electronic gain through an automatic gain control (AGC) so that  $H_{nems}H_{elec}=1$ . In our approach, the intrinsic nonlinearities of the electronic circuit are used to stabilize the oscillation without the need of an AGC. However, this approach requires special attention in the design of the electronics to ensure the functionality of the whole system.

#### **4 Implementation, design of the feedback loop**

The aim of the electronic circuit is to amplify and phase-shift the circuit input voltage ( $v_e$ ). As shown in section 3, the phase-shift between  $v_N$  and  $v_e$  must be of  $\pi/2$  and the gain of the circuit  $G_{elec} > \frac{1}{g_{nems}} = \frac{1}{0.93}$  $>$  $\frac{1}{2}$  =  $\frac{1}{2}$  $G_{elec} > \frac{1}{g_{nems}} = \frac{1}{0.93}$ . This can be achieved with the schematic shown in figure 1 [6]. The input voltage  $v_e$  is applied on the gate of the transistor  $M_0$  and converted into a current which flows into the output capacitor  $(C_{out})$ ; this schemeshifts the phase of the output voltage  $v_N$ . The transistors  $M_P$  and  $M_I$  act respectively as a current source and a resistance that polarize the transistor  $M_0$ .  $M_{\text{lds}}$  is polarized by an external DC voltage. The admittances of  $M_P$  and  $M_{\text{lds}}$  are respectively  $1/(g_{dsP}+g_{mP})$  (active charge configuration) and  $1/g_{dsI}$  (current source configuration). To achieve a capacitive-input electronic circuit, as assumed in section 2, the admittance of  $M_P$  must be negligible compared to the input capacitance  $C_{in}$  of the circuit (mainly parasitic). For the motional current to flow into  $C_{out}$ , the drain-source admittances of  $M_{\text{lds}}(q_{\text{ds}})$  and  $M_0(q_{\text{ds}})$  must be negligible compared to the equivalent

admittance of  $C_{out}$ . Finally the gate-drain capacitance  $C_{gd0}$  of  $M_0$  must be small compared to  $C_{in}$ . These conditions sum up to:

$$
g_{dsP} + g_{gP} \ll 2\pi f_0 C_{in} , \qquad g_{ds0} + g_{dsI} \ll 2\pi f_0 C_{out} \text{ and } C_{gd0} \ll C_{in} . \tag{8}
$$

A trade-off must be found on the value of  $C_{out}$  in order to obtain a high gain while keeping its equivalent admittance larger than  $q_{\text{lds}}$ . The transistors dimensions must be optimized to fulfill (8). The polarization voltage of  $M_{\text{lds}}$  can be set to ensure that the gate and drain DC voltages of  $M_0$  are equal while keeping the transistors in the saturation regime: this ensures that the DC component of  $V_N$  and  $V_e$  are equal (what does not statically deflect the beam since equal dc voltages are applied on each side of the beam).

Finally the dimensions of the transistor  $M_P$  must be set in order to obtain low  $g_{dsP}$  and  $g_{\text{mP}}$  values. With  $C_{in}$  typically in the order of 10pF, simulations show that the following values:

 $g_{m0} = 36\mu S$ ,  $g_{ds0} = 0.5\mu S$ ,  $C_{gd0} = 160\,fF$ ,  $g_{ds} = 0.1\mu S$ ,  $g_{ds} = 0.3\mu S$  and  $C_{out} = 400\,fF$ , (7) obey to the constraints imposed by (8). According to these values and assuming  $f \approx f_0$ , the small-signal electronic gain and phase are  $G_{elec}=1.15$ ,  $\Psi_{elec}=92^\circ$ . Oscillations in the system therefore build up. In the next section, we will determine the characteristics of the steady-state regime.

#### **5 Amplitude of stabilized oscillations**

Using the describing function method [7], we have analyzed the theoretical circuit response  $v_{\text{N}}=f(v_{e})$  for a large input voltages range at a specific frequency, i.e. the NEMS fundamental frequency  $f_0$ , by performing transient simulations. The Fourier coefficient of this signal at the fundamental frequency  $f_0$  is then calculated in order to obtain the gain and the phase of the output signal.



The circuit response is depicted in terms of voltage gain  $(v_n/v_e)$  and phase in Figure 2. The transfer function  $H_{elec}(v_e, i2\pi f_0)$  is therefore described. It shows that the electronic circuit has a linear behavior when  $v_e$  is lower than 30mV. For higher values, the circuit gain decreases and its phase increases. Whereas the total loop gain of the oscillator is higher than one in the linear part of the response, a gain strictly equal to one can be obtained in the nonlinear saturated part. Knowing  $q_{nems}(v_e)$  and  $\Psi_{elec}(v_e)$  and using (8), one may then plot  $G_{elec}$  and  $1/G_{nems}$  versus  $v_e$ using the fact that, in the steady state,  $\Psi_{nems}(f)$  should be equal to  $-\psi_{elec}(v_e)$ . The existence of a steady state regime can then be determined from the intersection of

 $G_{elec}(v_e)$  and  $1/G_{nems}(v_e)$  (figure 3). The intersection corresponds to a stable displacement amplitude of the beam of about 80nm (which is far from the pull-in threshold) and an electronic output voltage amplitude of about 90mV.

This technique is a fairly simple method to evaluate the stabilized amplitude of NEMS oscillators. However in this study, the Duffing effect and the electrostatic nonlinearity have been neglected in this study as we have assumed that  $y < g$ . These assumptions can lead to an error up to 25% on the NEMS transfer function.



Figure 3: Evolution of  $G_{elec}$  and  $1/G_{nems}$  versus  $v_e$  at  $\Psi_{nems}(f)=\Psi_{elec}$ .

## **6 Conclusion**

In this paper, the theoretical study of an ultra-compact NEMS/CMOS oscillator is presented. The oscillation conditions are calculated based on (i) the electromechanical modeling of the nano-mechanical resonator and (ii) on the behavior of a dedicated CMOS sustaining amplifier circuit designed for this purpose. After briefly analyzing this electronic circuit design, this paper focuses on the study of the saturation mechanisms of the mechanical oscillations to avoid pull-in effect. This has been done using the "describing function" method applied to the CMOS circuit..

[1] M. Gad-el-Hak, The MEMS Handbook, 2nd ed. Boca Raton, FL: CRC, 2005.

[2] J.D. Taylor et al. in Frontiers in Nanoscience and Nanotechnology, Eds. Anant Narlikar and Yunyi Fu, Oxford University Press (submitted).

[3] O. Brand, Proceedings IEEE, vol. 94, no. 7, pp. 1160-1176, Jul. 2006

[4] J. Verd, et al, J. Microelectromech. Syst., vol. 14, p. 508, Jun. 2006.

[5] J. Arcamone, et al, Nanotechnology, vol. 19, 305302, Jul. 2008

[6] E. Colinet, et al, Journal of Applied Physics, vol. 105, no. 12, pp 124908-8, 2009

[7] A. Gelb, et al, Mcgraw-Hill, New-York, 1968.